

Docket No.: 2336-182



IFW
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kyu Yeon PARK *et al.*

U.S. Patent Application No. 10/601,775

Filed: June 24, 2003

: Confirmation No. 9497

: Group Art Unit: 2811

: Examiner: Ori Nadav

For: MICRO-ELECTRO MECHANICAL SYSTEMS (MEMS) DEVICE USING SILICON ON INSULATOR (SOI) WAFER, AND METHOD OF FABRICATING AND GROUNDING THE SAME

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

By Official Action mailed *July 2, 2004*, restriction to one of the following inventions is required under 35 USC 121:

- I. Claims 1-5, drawn to a semiconductor device, classified in class 257, subclass 415.
- II. Claims 6-13, drawn to a process of making a semiconductor device, classified in class 438, subclass 22+.

In response, Applicants hereby elect Group I, upon which claims 1-5 are readable, for examination in this case. A divisional application will be filed for Group II in due course.

Early examination on the merits is courteously solicited.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper,

including extension of time fees, to Deposit Account 07-1337 and please credit any excess fees to such deposit account.

Respectfully submitted,

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